Inventor: Park

Title: "Method of Forming a Trench in a Semiconductor Device"
Attorney Docket No.: 20067/OPP031475US
Sheet 1 of 3

FIGURES

Fig. 1a

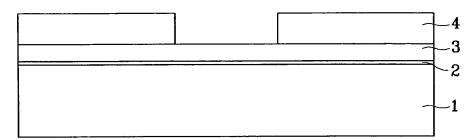


Fig. 1b

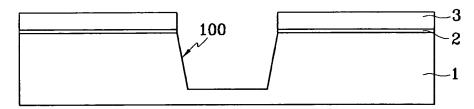


Fig. 1c

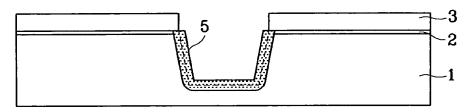
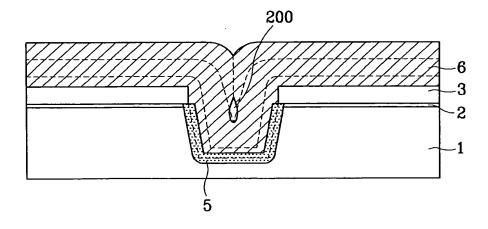


Fig. 1d



Inventor: Park

Title: "Method of Forming a Trench in a Semiconductor Device"
Attorney Docket No.: 20067/OPP031475US
Sheet 2 of 3

Fig. 2a

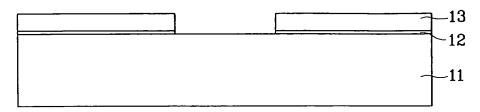


Fig. 2b

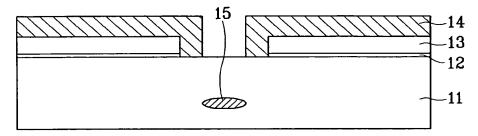


Fig. 2c

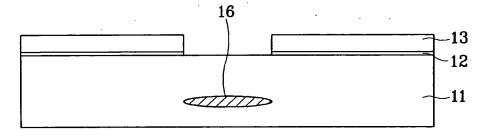
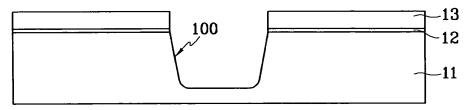


Fig. 2d



Inventor: Park

Title: "Method of Forming a Trench in a Semiconductor Device"
Attorney Docket No.: 20067/OPP031475US
Sheet 3 of 3

Fig. 2e

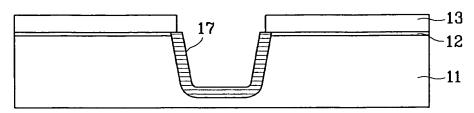


Fig. 2f

